AMENDMENTS TO THE CLAIMS:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Original) A composition for forming anti-reflective coating characterized by containing a compound of formula (1)

$$R_2OH_2C$$

N

 CH_2OR_1

Formula (1)

wherein R_1 and R_2 are independently of each other hydrogen atom or an alkyl group, R_3 and R_4 are independently of each other hydrogen atom, methyl group, ethyl group, hydroxymethyl group or an alkoxymethyl group.

- 2. (Original) A composition for forming anti-reflective coating characterized by containing a resin produced from the compound of formula (1) according to claim 1.
- 3. (Original) The composition for forming anti-reflective coating according claim 2, wherein the resin is a condensation product produced from the compound of formula (1).
- 4. (Currently Amended) The composition for forming anti-reflective coating according to any one of claims 1 to 3 claim 1, further containing a light absorbing compound and/or a light absorbing resin.

- 5. (Original) The composition for forming anti-reflective coating according to claim 4, wherein the light absorbing compound is at least one compound selected from naphthalene compounds and anthracene compounds.
- 6. (Original) The composition for forming anti-reflective coating according to claim 4, wherein the light absorbing compound is at least one compound selected from triazine compounds and triazine trione compounds.
- 7. (Original) The composition for forming anti-reflective coating according to claim 4, wherein the light absorbing resin is a resin having in the structure at least one aromatic ring structure selected from benzene ring, naphthalene ring and anthracene ring.
- 8. (Currently Amended) The composition for forming anti-reflective coating according to any one of claims 1 to 3 claim 1, further containing a resin having at lease one crosslink-forming substituent selected from hydroxy group, carboxy group, amino group and thiol group.
- 9. (Currently Amended) The composition for forming anti-reflective coating according to any one of claims 1 to 3 claim 1, further containing an acid and/or acid generator.
- 10. (Currently Amended) A method of forming an anti-reflective coating for use in a manufacture of a semiconductor device, characterized by comprising the steps of: coating the composition for forming anti-reflective coating according to any one of claims 1 to 3 claim 1 on a substrate, and baking it.

11. ..(Currently Amended) A process for manufacturing a semiconductor device, characterized by comprising the steps of:
coating the composition for forming anti-reflective coating according to any one of claims 1
to 3 claim 1 on a substrate and baking it to form an anti-reflective coating;
forming a photoresist on the anti-reflective coating;
exposing the substrate covered with the anti-reflective coating and the photoresist with a light;
developing it;

transferring an image on the substrate by etching to form an integrated circuit device.